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## INFORMATION

Applicant : Horacio D. Espinosa et al.

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## DISCLOSURE

Serial No.: 10/801 928

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## U.S. PATENT DOCUMENTS

Examiner Initial*	Document Number	Date	Name	Class	Sub Class	Filing Date

## FOREIGN PATENT DOCUMENTS

Examiner Initial*	Document Number	Date	Country	Class	Sub Class	Translation Y/N

## OTHER DOCUMENTS (Including Author, Title, Date, Pages, Etc.)

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<i>du</i>	AI	Piner, R. et al., "'Dip-Pen' Nanolithography," Science 283, Jan 1999, p. 661-663.
	AJ	Rangelow, I. et al., "'NANOJET': Tool for the nanofabrication," J. Vac. Sci. Technol. B 19(6), Nov/Dec 2001, p. 2723-2726.
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<i>du</i>	AO	Zou, J. et al., "Conductivity-based contact sensing for probe arrays in dip-pen nanolithography," Appl. Phys. Lett. 83(3), Jul 2003, p. 581-583.

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